

**Notice of References Cited**

Application/Control No.

10/589,399

Applicant(s)/Patent Under  
Reexamination  
LU ET AL.

Examiner

YOSHITOSHI TAKEUCHI

Art Unit

1793

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Yan et al, Microstructure of Surface Layers in Cu(In,Ga)Se <sub>2</sub> Thin Films, NREL/CP-520-33615 (May 2003).
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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